

applications is corrected to read March 24, 1995.

FOR FURTHER INFORMATION, CONTACT:
Demetrice Jenkins at (214) 767-8001.

11.801 Native American Program
(Catalog of Federal Domestic Assistance)
Dated: March 3, 1995.

Donald L. Powers,

Federal Register Liaison Officer, Minority Business Development Agency.

[FR Doc. 95-5679 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-21-P

Native American Business Development Center Applications: New Mexico

AGENCY: Minority Business Development Agency, Commerce.

ACTION: Correction.

SUMMARY: On page 9665, in the issue dated February 21, 1995, third column, second paragraph, the closing date for applications is corrected to read March 24, 1995.

FOR FURTHER INFORMATION, CONTACT:
Demetrice Jenkins at (214) 767-8001.

11.801 Native American Program
(Catalog of Federal Domestic Assistance)
Dated: March 3, 1995.

Donald L. Powers,

Federal Register Liaison Officer, Minority Business Development Agency.

[FR Doc. 95-5678 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-21-P

Native American Business Development Center Applications: Oklahoma

AGENCY: Minority Business Development Agency, Commerce.

ACTION: Correction.

SUMMARY: On page 9668, second column, first paragraph, the closing date for applications is corrected to read March 24, 1995.

FOR FURTHER INFORMATION, CONTACT:
Demetrice Jenkins at (214) 767-8001.

11.801 Native American Program
(Catalog of Federal Domestic Assistance)
Dated: March 3, 1995.

Donald L. Powers,

Federal Register Liaison Officer, Minority Business Development Agency.

[FR Doc. 95-5680 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-21-P

National Institute of Standards and Technology

Announcement of an Opportunity To Join a Cooperative Research and Development Consortium for Alternative Approaches to Nanometer-Level Overlay and CD Metrology for IC Manufacturing

AGENCY: National Institute of Standards and Technology, Commerce.

ACTION: Notice of public meeting and notice of Government owned invention available for licensing.

SUMMARY: The National Institute of Standards and Technology (NIST) invites interested parties to attend a meeting on April 26, 1995 to discuss the possibility of setting up a cooperative research consortium to develop innovative approaches to overlay and CD metrology consistent with SIA-projected requirements. Parties interested in participating in the consortium should be prepared to invest adequate resources in the collaboration and be firmly committed to the goal of developing innovative approaches.

The program will be within the scope and confines of The Federal Technology Transfer Act of 1986 (Public Law 99-502, 15 U.S.C. 3710a), which provides Federal laboratories including NIST, with the authority to enter into cooperative research agreements with qualified parties. Under this law, NIST may contribute personnel, equipment and facilities—but no funds—to the cooperative research program.

Members will be expected to make a contribution to the consortium's efforts in the form of materials, equipment, personnel, and/or funds. The program is expected to last 18 months. This is not a grant program.

DATES: Interested parties should contact NIST to confirm their interest at the address, telephone number or FAX number shown below no later than April 7, 1995.

ADDRESSES: Technology Building, Room B360, National Institute of Standards and Technology, Gaithersburg, MD 20899.

FOR FURTHER INFORMATION CONTACT: Michael W. Cresswell, Telephone: 301-975-2072; FAX: 301-948-4081.

SUPPLEMENTARY INFORMATION: The National Institute of Standards and Technology (NIST) invites interested parties to participate in a cooperative research consortium to conduct modeling of overlay detection by electrostatic/magnetic sensors interacting with optical metrology target architectures commonly used in

advanced IC manufacturing, examine enhancements deriving from target-geometry modifications and sensor-head innovations, design and evaluate a test implementation using Maxwell-equation-based simulation software and formulate specifications of a candidate design for selected applications.

In conjunction with the opportunity to join this Cooperative Research and Development Consortium, the following invention is available for licensing:

NIST Docket No. 94-040CIP

Title: Method and Reference Standards for Measuring Overlay in Multilayer Structures, and for Calibrating Imaging Equipment as Used in Semiconductor Manufacture.

Description: Imaging instruments for overlay-measurement extraction from partially-processed semiconductor wafers, are calibrated by providing a reference test structure having features which can be located by electrical measurements not subject to tool-induced shift and water-induced shift experienced by the imaging instrument. The reference test structure is first qualified using electrical measurements, and is then used to provided the effect of the said shifts on the imaging-instrument measurements.

Dated: March 1, 1995.

Samuel Kramer,

Associate Director.

[FR Doc. 95-5662 Filed 3-7-95; 8:45 am]

BILLING CODE 3510-13-M

Patent and Trademark Office

National Information Infrastructure (NII) Copyright Awareness Campaign

AGENCY: Patent and Trademark Office, Commerce.

ACTION: Notice of meeting.

SUMMARY: The Working Group on Intellectual Property Rights of the White House Information Infrastructure Task Force (ITTF) issued a preliminary draft of its report, "Intellectual Property and the National Information Infrastructure," on July 7, 1994. One of the Working Group's findings announced in the preliminary draft is that effective education of the public about intellectual property rights is crucial to the successful development of the NII. The Working Group recognizes that the public's awareness of their own intellectual property rights, as well as those of others, will lead to increased respect for those rights.

In order to effectuate public awareness of copyright, the preliminary draft, on page 140, stated that the